

Electronic Supplementary Material

Laser polishing of a high-entropy alloy manufactured by selective laser melting

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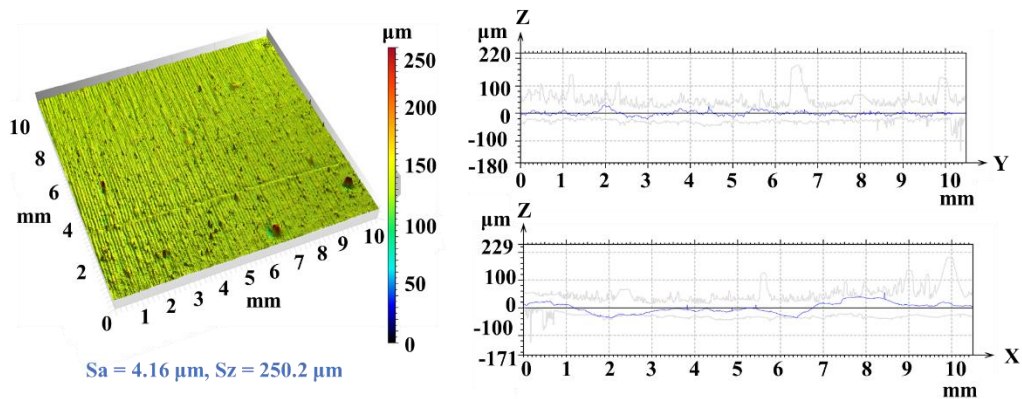


Fig. S1 3D surface profile of as-SLMed surface with an area of $10.49 \text{ mm} \times 10.49 \text{ mm}$.